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AMENDMENT UNDER 37 CFR 1.116  
EXPEDITED PROCEDURE -  
TECHNOLOGY CENTER 1700

Box AF  
Assistant Commissioner for Patents  
Washington, D.C. 20231

**PATENT**  
Attorney Docket No.: 018867-000410US

On October 10 2002

TOWNSEND and TOWNSEND and CREW LLP

By: [Signature]

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of:

SHUZO FUJIMURA et al.

Application No.: 09/328,939

Filed: June 9, 1999

For: SURFACE TREATMENT  
METHOD AND EQUIPMENT

Examiner: Shamim Ahmed

Art Unit: 1746

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OFFICE OF PETITIONS

AMENDMENT UNDER 37 CFR 1.116  
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TECHNOLOGY CENTER 1700

Box AF  
Assistant Commissioner for Patents  
Washington, D.C. 20231

Sir:

In response to the Final Office Action mailed July 1, 2002, please amend this application as follows:

**IN THE CLAIMS:**

Please amend claims 1 and 5, cancel claim 3, and add new claims 23-29 as follows:

1. (Amended) A method of surface treatment in a substantially downstream position of a plasma source to substantially be free from an undesirable influence of a reactive species from the plasma source, where an object to be processed is downstream from the plasma source, the method comprising generating a plasma